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Chiu

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(54) **APERTURE PLATE OF VACUUM CHAMBER FOR AN ELECTRON MICROSCOPE**

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(**) Term: **15 Years**

(21) Appl. No.: **29/761,610**

(22) Filed: **Dec. 10, 2020**

(51) **LOC (13) Cl.** **16-06**

(52) **U.S. Cl.**
USPC **D16/136**

(58) **Field of Classification Search**
USPC D16/100, 130, 131, 132, 134, 133, 135, D16/136, 219, 245, 310, 340; D24/137, D24/150, 157, 172
CPC ... G02B 7/00; G02B 7/02; G02B 7/04; G02B 25/00; G02B 25/002; G02B 25/004; G02B 25/007; G02B 25/008
See application file for complete search history.

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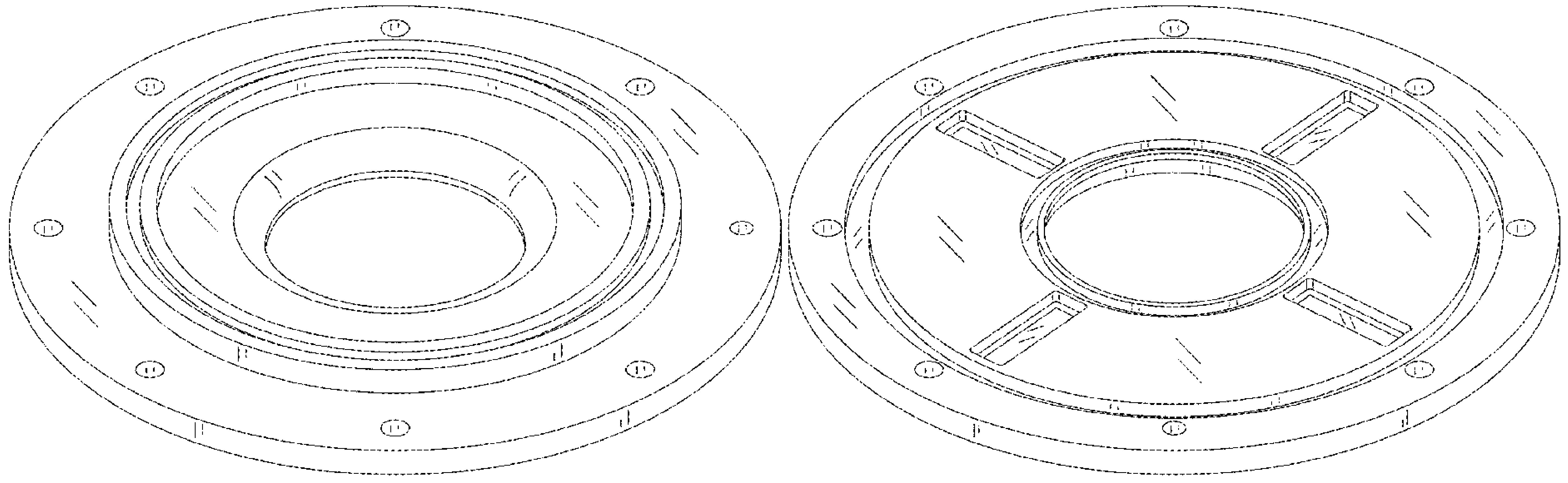
(57) **CLAIM**

The ornamental design for an aperture plate of vacuum chamber for an electron microscope, as shown and described.

DESCRIPTION

FIG. **1** is a top perspective view of an aperture plate of vacuum chamber for an electron microscope showing my new design;
FIG. **2** is a bottom perspective view thereof;
FIG. **3** is a front elevational view thereof, the rear, left and right side elevational views being mirror images thereof;
FIG. **4** is a top plan view thereof;
FIG. **5** is a bottom plan view thereof; and,
FIG. **6** is a perspective view of the aperture plate of vacuum chamber for an electron microscope in a condition of use.
The broken lines showing of the aperture plate of vacuum chamber for an electron microscope is for the purpose of illustration portions of the article and forms no part of the claimed design.

1 Claim, 6 Drawing Sheets



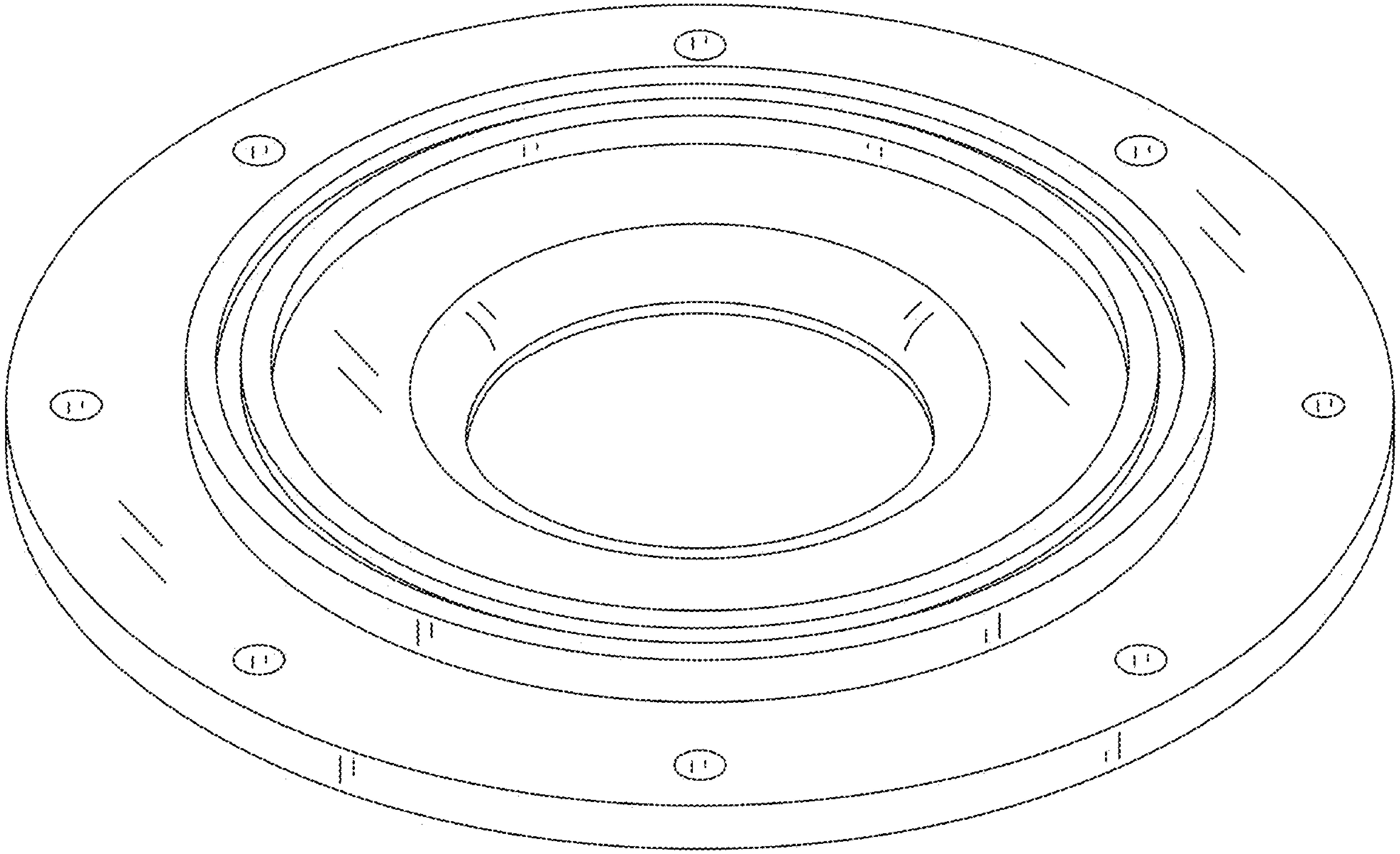


FIG. 1

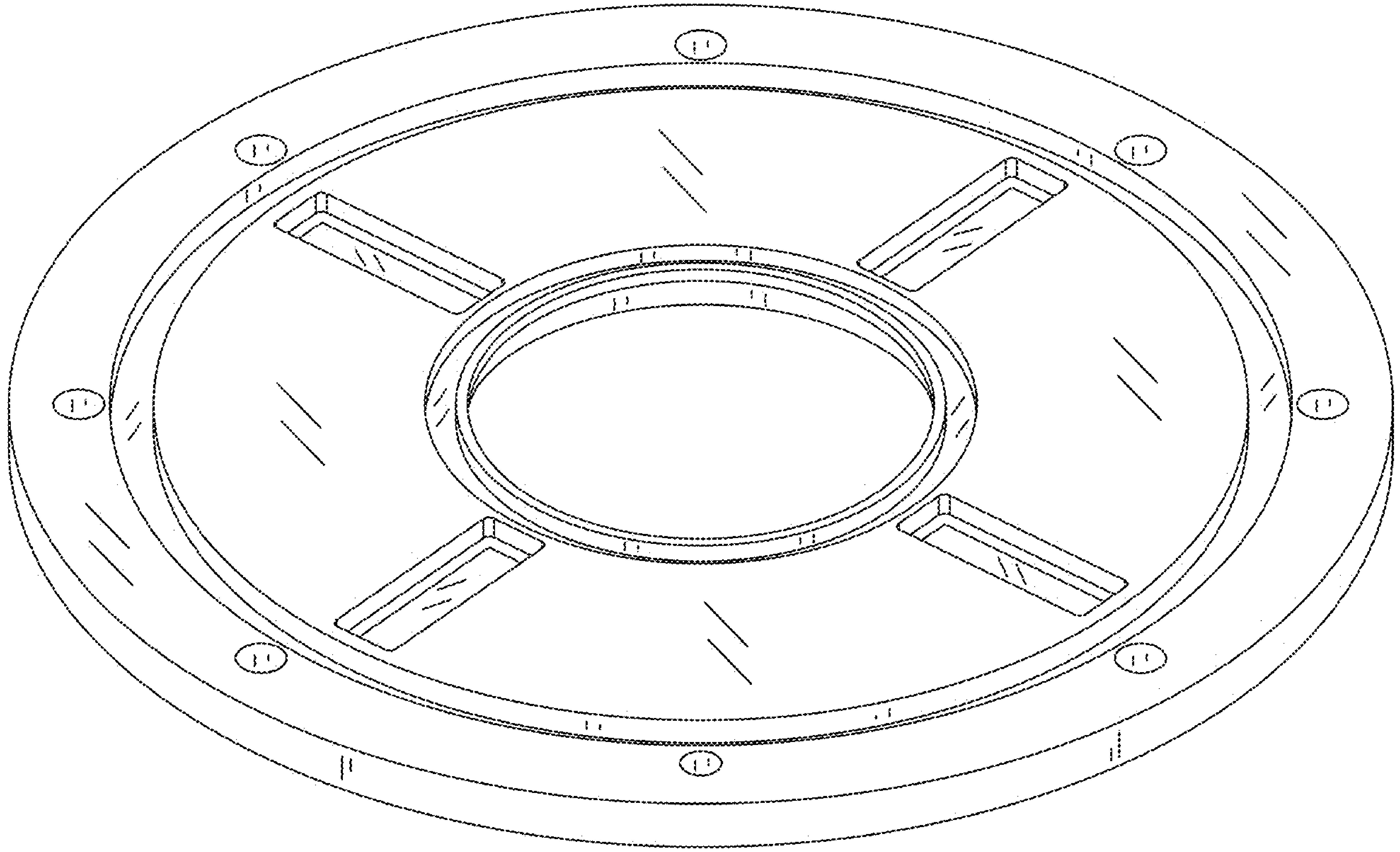


FIG. 2

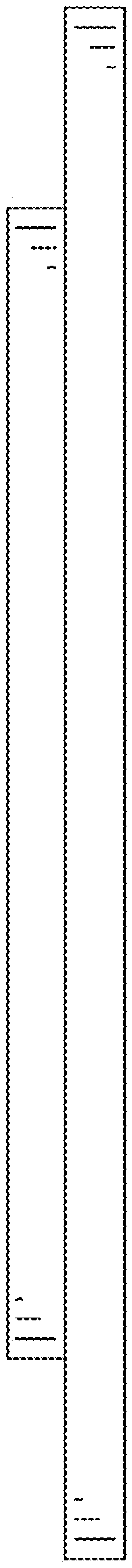


FIG. 3

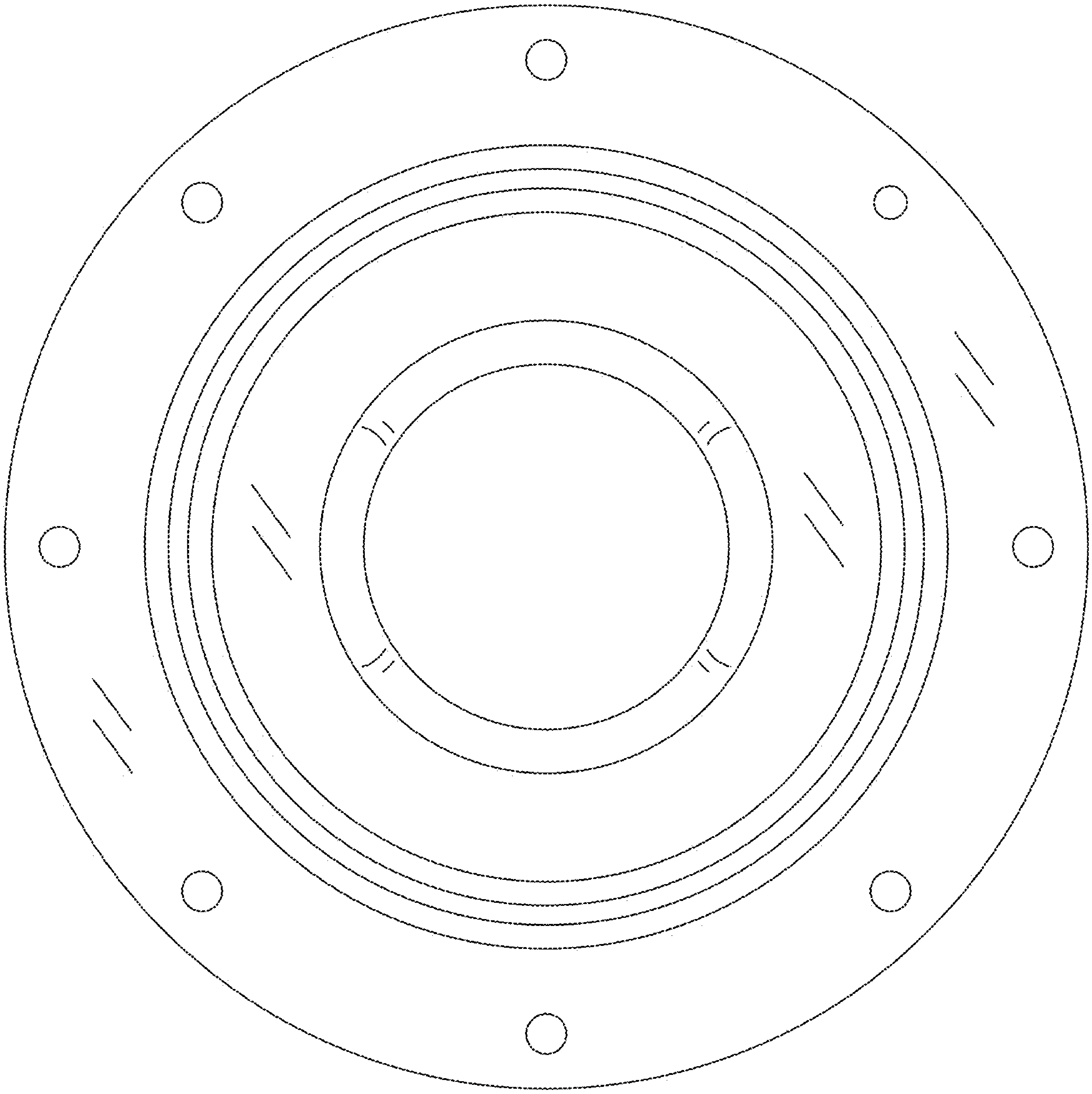


FIG. 4

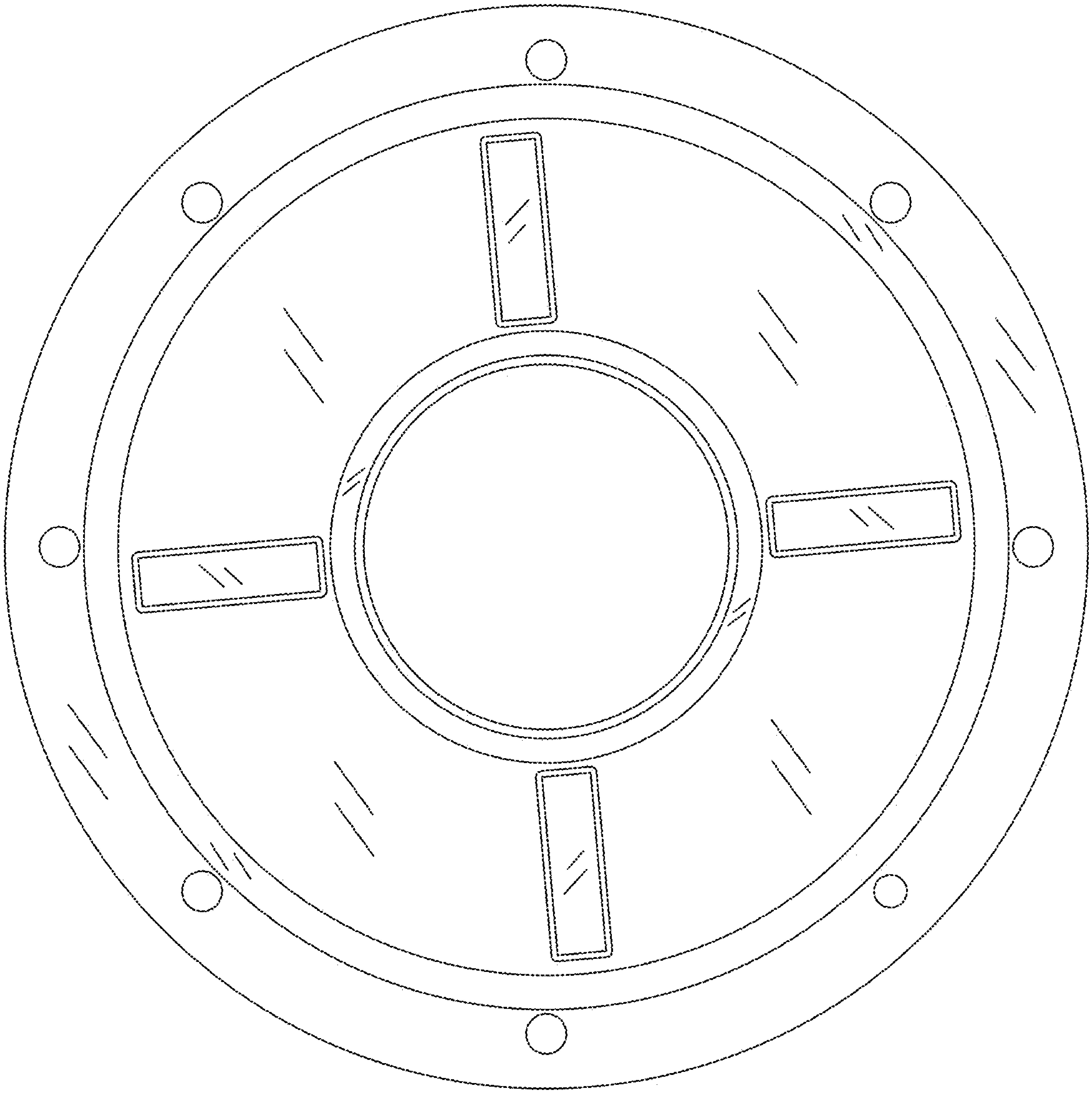


FIG. 5

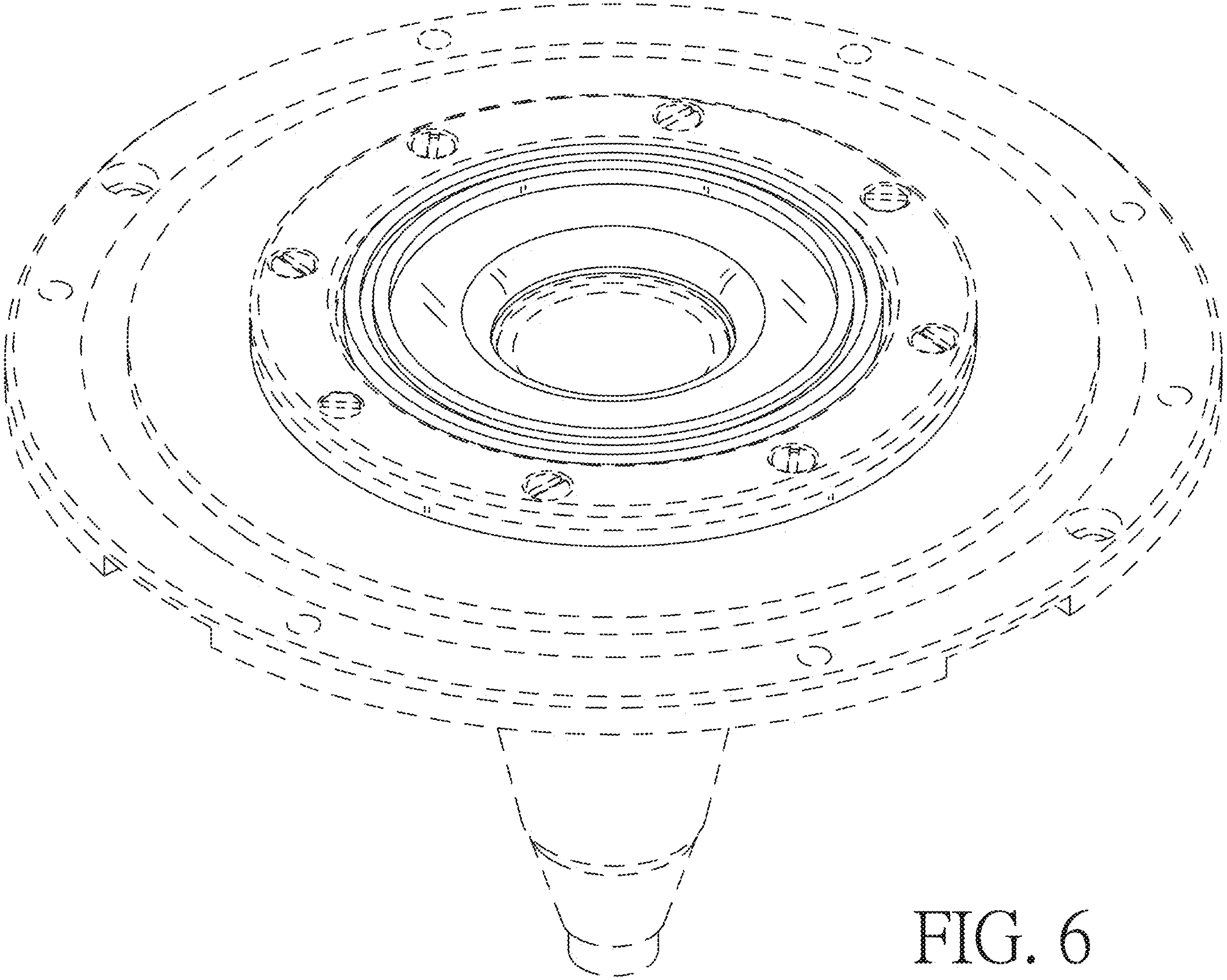


FIG. 6